

Imaging polarimeter systems for the automatic measurement of residual stresses in optical materials

In industrial optics, especially in the field of microlithography, highly homogeneous optical materials are used. Through the effect of stress birefringence, residual stresses influence the polarization of light, which is an undesirable effect in many applications. Therefore, constant testing of residual stress is a very important part of quality control.

The new StrainMatic® M4 series automatizes the measurement and evaluation of the stress birefringence and enables a fast and exact determination of the stress distribution in optical materials and components.



Your Benefits

Objective results

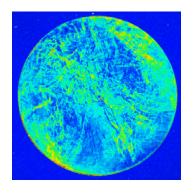
Fast and easy operation

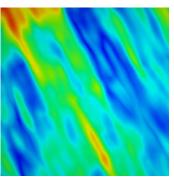
Improvement in quality by on-site measurement

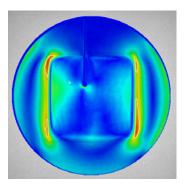
Traceability by automatic filing of all parameters and results

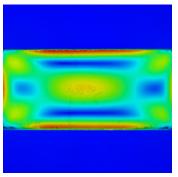
Cost reduction by optimization of the production process











Technical Data

StrainMatic® M4/300

approx. 550 x 920 x 670 mm (H/W/D)
LED Array, approx. 400 x 320 mm
CCD camera (640 x 480 pixels) with telecentric lens (300 mm aperture)
approx. 232 x 174 mm (0.36 pixel distance, 8 pixel/mm²)
variable rectangular, round or elliptical
polarization angle (°) optical retardation (nm) normalized optical retardation (nm/cm) normalized stress (MPa)
approx290 to +290 nm optical retardation optional -2900 to +2900 nm (HOD module)
typical <±0.1 nm (mean deviation)
Ethernet, USB, VGA
230 V, 50 Hz or 115 V, 60 Hz
approx. 2210 x 1050 x 850 mm (H/W/D)
approx. 400 kg (incl. base frame)

Application Examples

Optical materials (e.g. fused silica, Al_2O_3 , CaF_2 , BaF_2 , MgF_2)

Optical components (e.g. lenses, windows, prisms)

Tubing glass and related products (e.g. lab glass, reaction tubes)

Custom adaptations and special versions are possible on request. No responsibility is taken for the correctness of the information. All information is subject to change without prior notice.

Product website: www.ilis.de/en/strainmatic.html © 2008 ilis gmbh, all rights reserved. Version 04/2008

